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**(54) CONTAMINATION MONITOR FOR IMAGE FORMING APPARATUS**

**(57) Abstract:**

**PROBLEM TO BE SOLVED:** To provide a contamination monitor for an image forming apparatus capable of obtaining information to monitor a contaminating state of a component for forming an image and to clarify a type, a generation source and a generating state of a contaminant.

**SOLUTION:** The contamination monitor for the image forming apparatus comprises a high refractive index material 2 which has a large refractive index and which is transparent in an infrared region, an infrared ray source 1, a detector 3 and a reflecting mirror 4. The infrared ray IR is passing through the material 2 provided in the image forming apparatus while repeating total reflecting.

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